

CHARACTERIZATION OF TRENCH SCHOTTKY DIODE WITH TRENCH BOTTOM OXIDE (TBO) PROCESS

This thesis is presented in partial fulfillment for the award of the

Bachelor of Engineering (Hons.) Electronic

UNIVERSITI TEKNOLOGI MARA



**NURUL IZZATI BT MOHAMMAD NOH
FACULTY OF ELECTRICAL ENGINEERING
UNIVERSITI TEKNOLOGI MARA,
40450 SHAH ALAM,
SELANGOR, MALAYSIA
JULY 2012**

ACKNOWLEDGEMENT

In the name of Allah S.W.T, the Most Beneficent and Merciful

First and foremost, I praise to the almighty Allah s.w.t for blessing me with a great experience, good health and great safety during my research. Million of thanks and appreciation to Universiti Teknologi MARA, Malaysia (UiTM) and MIMOS Bhd, for giving me an opportunity and providing the necessary facilities in completing this research.

I would like to express my highest appreciation to my supervisor, Pn. Maizatul Zolkapli for generous guidance, cooperation, support and advices from time to time throughout the duration of this research.

I would also to express my sincere appreciation and gratitude to my supervisor at MIMOS Bhd, En. Mohd Rofei Mat Hussin for the kind support, guidance, cooperation and giving me opportunity to gain experience on research area in MIMOS Bhd. I greatly appreciate those valuable help and knowledge with al aspect of this thesis.

Special thanks to entire staffs at MIMOS, especially clean room and test lab staffs for their continuous support, kind help, cooperation and idea to guide and complete this project.

I am especially to gracious help and concern of my course mate who shared together the information and opinion to do this thesis.

I am deeply gratefully to my parent whose love and moral support has given me great inner strength, encouragement and motivation to succeed. Last but not least, I would like to say thank you for the endless support that you had given me. Thank you.

ABSTRACT

A new Schottky diode structure namely as TBO Trench Schottky diode is proposed. Introduction of TBO process to the Trench Schottky diode has shown better device characteristics. In this study, the Trench Bottom Oxide (TBO) process was developed in order to increase reverse blocking voltage of Schottky diode. The process characterization on Trench Bottom Oxide (TBO) for Trench Schottky diode has been done to determine the I - V characteristic. Besides that, the device characterization analysis on Trench Schottky diode with and without TBO process is performed. As a result from the study, an improved reverse blocking voltage has been achieved. TBO layer in trench structure can reduce the electric field crowding at the corner of trench bottom then increased the breakdown voltage. From experimental results, breakdown voltage for Schottky diode structure with TBO is about -64.50V whereas the Schottky diode structure without TBO is around -60.50V. There is about 4V difference of breakdown voltage due to TBO effect. Another important factor that also determines the breakdown voltage of Schottky diode is gate oxide thickness. Thicker gate oxide demonstrating higher breakdown voltage.

TABLE OF CONTENTS

LIST OF TITLE	PAGE
DECLARATION	i
DEDICATION	ii
ACKNOWLEDGMENT	iii
ABSTRACT	iv
TABLE OF CONTENT	v
LIST OF FIGURES	vii
LIST OF ABBREVIATIONS	ix
LIST OF SYMBOLS	ix

CHAPTER ONE: INTRODUCTION

1.1	BACKGROUND OF STUDY	1
1.2	PROBLEM STATEMENT	4
1.3	SIGNIFICANCE OF STUDY	5
1.4	OBJECTIVE OF STUDY	5
1.5	SCOPE OF WORK	5
1.6	THESIS ORGANIZATION	6

CHAPTER TWO: LITERATURE REVIEW

2.1	LITERATURE REVIEW	8
2.2	CONVENTIONAL SCHOTTKY DIODE	8
2.3	TRENCH MOS BARRIER SCHOTTKY (TMBS) DIODE	9
2.4	TRENCH BOTTOM OXIDE (TBO) THICKNESS	12
2.5	SCHOTTKY BARRIER	14
2.6	PN JUNCTION AND DIODE	15

CHAPTER ONE

INTRODUCTION

1.1 BACKGROUND OF STUDY

Schottky diode is formed when metal is brought in contact with lightly doped n-type semiconductor material. Schottky diode also known as hot carrier because it has majority carriers that are injected from the n-type to the metal (L. Poole 2011). When metal-semiconductor junction is formed the electron from the semiconductor will flow across the junction and fill the free energy state in the metal. This electron flows across the junction will create the depletion region between the metal and semiconductor. The difference in the energy level of work function between the metal and semiconductor is called as Schottky barrier (Hu 2009). When under forward bias which means metal connected to positive in an n-doped Schottky, there are many electrons with sufficient thermal energy to cross the barrier potential into the metal.

When Schottky diode in condition reverse biased or negative biased applied, the potential barrier for electrons becomes wide. Hence, there is small possibility that an electron will have enough thermal energy to cross the junction. The reverse leakage current will be in nanoampere range (B. Baliga, Advanced Power Rectifier Concepts 2009). The mode operation of Schottky diode is quite different with the PN junction because of the minority carriers and diffusion process is not involved (Sparkes, Semiconductor devices:How they work 1987).